

Docket No.: 21776-00052-US1
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Nobuhiro Miki et al.

Confirmation No.: 6222

Application No.: 10/614,244

Filed: July 8, 2003

Art Unit: 1734

For: RESIST FILM REMOVAL APPARATUS AND
RESIST FILM REMOVAL METHOD

Examiner: Mark. A. Osele

OK to Enter

MAO 6-29-06

AMENDMENT AFTER FINAL ACTION UNDER 37 C.F.R. 1.116

MS AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the Final Office Action mailed April 10, 2006, finally rejecting claims 3, 4, 23, 26-34, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.

No fees are believed to be due with this amendment.